

Supporting Information

The Influence of Precursor on Rhenium Incorporation into Re-doped MoS₂ (Mo_{1-x}Re_xS₂) Thin Films by Aerosol-Assisted Chemical Vapour Deposition (AACVD).

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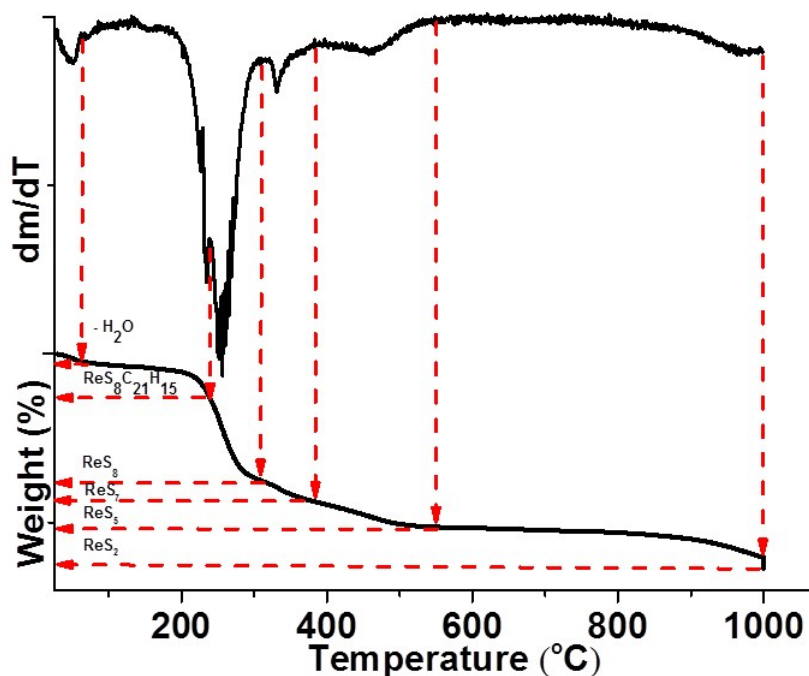


Figure S1 1st derivative of the TGA profile overlaid on TGA profile of [Re(S₂CC₆H₅)(S₃CC₆H₅)₂], (2).

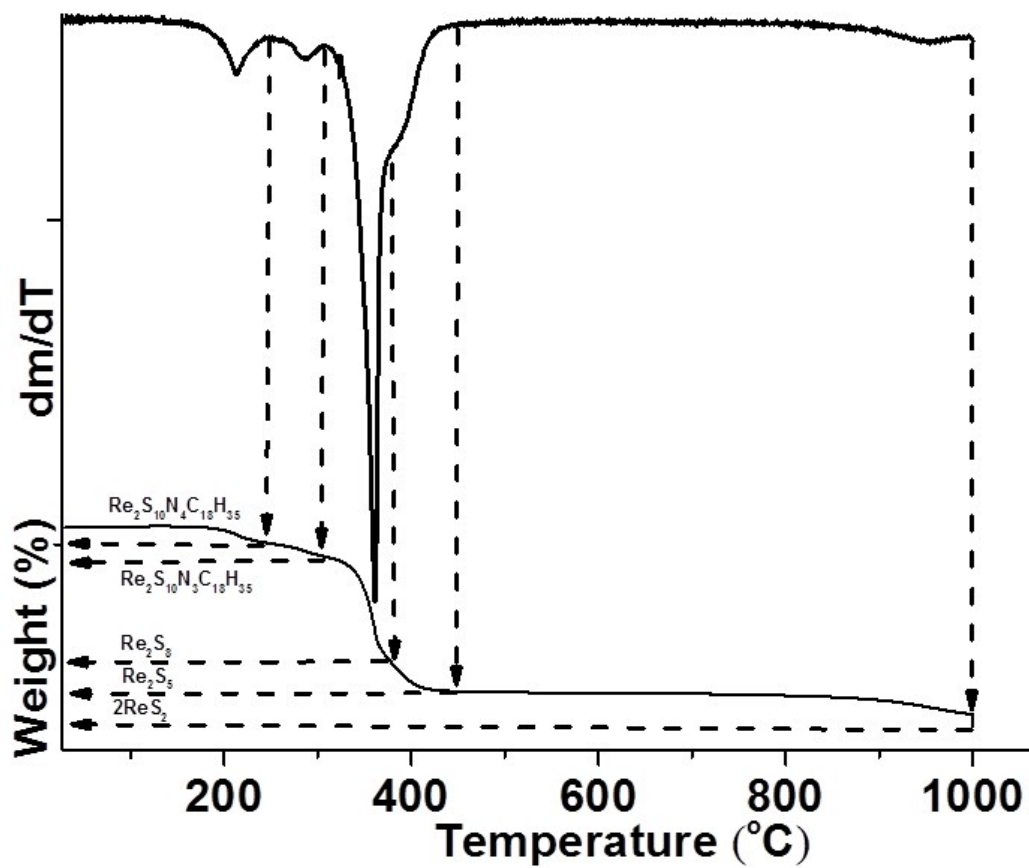


Figure S2 1st derivative of TGA profile overlaid onto the TGA profile of $[\text{Re}_2(\mu\text{-S})_2(\text{S}_2\text{CNEt}_2)_4]$ (3).

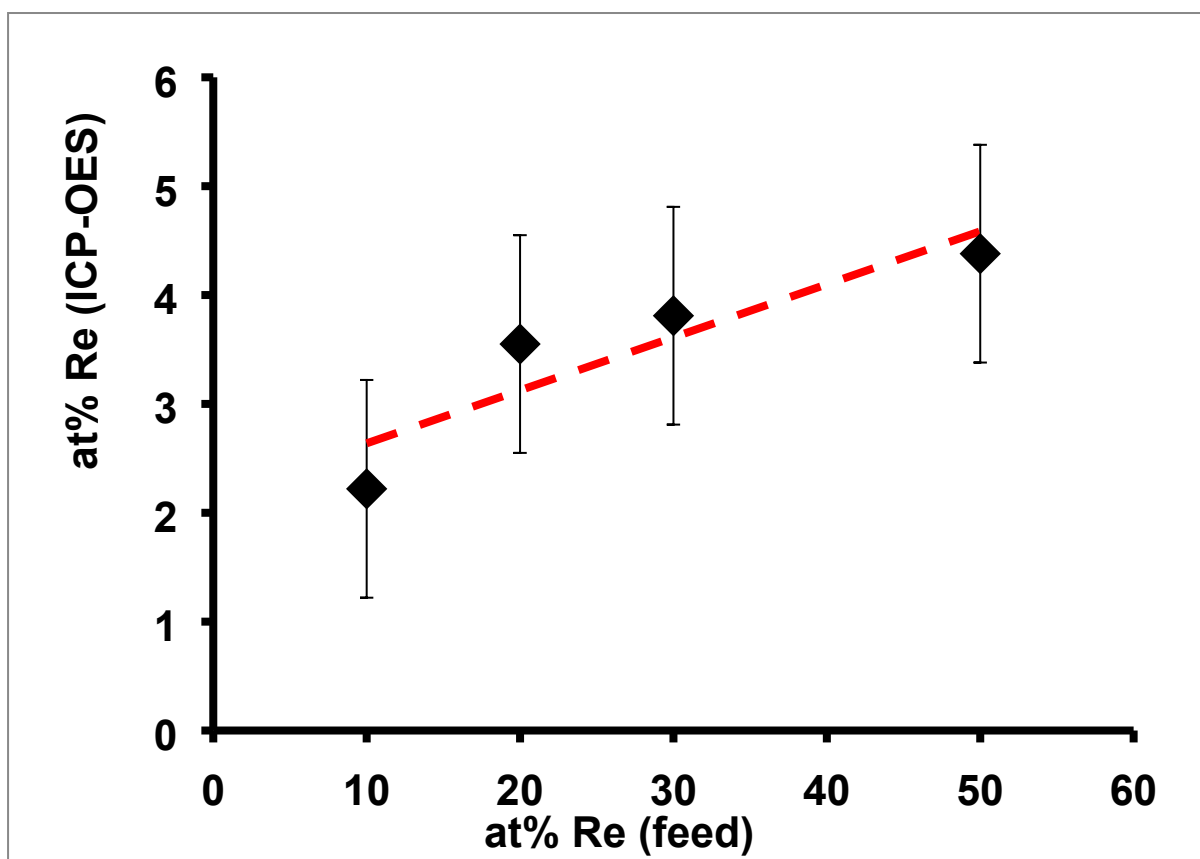


Fig. S3. The at% of Re that found using elemental analysis of thin films produced by AACVD using (1) and (2) at 550 °C by ICP-OE spectroscopies with varying Re mol% in the AACVD feed .

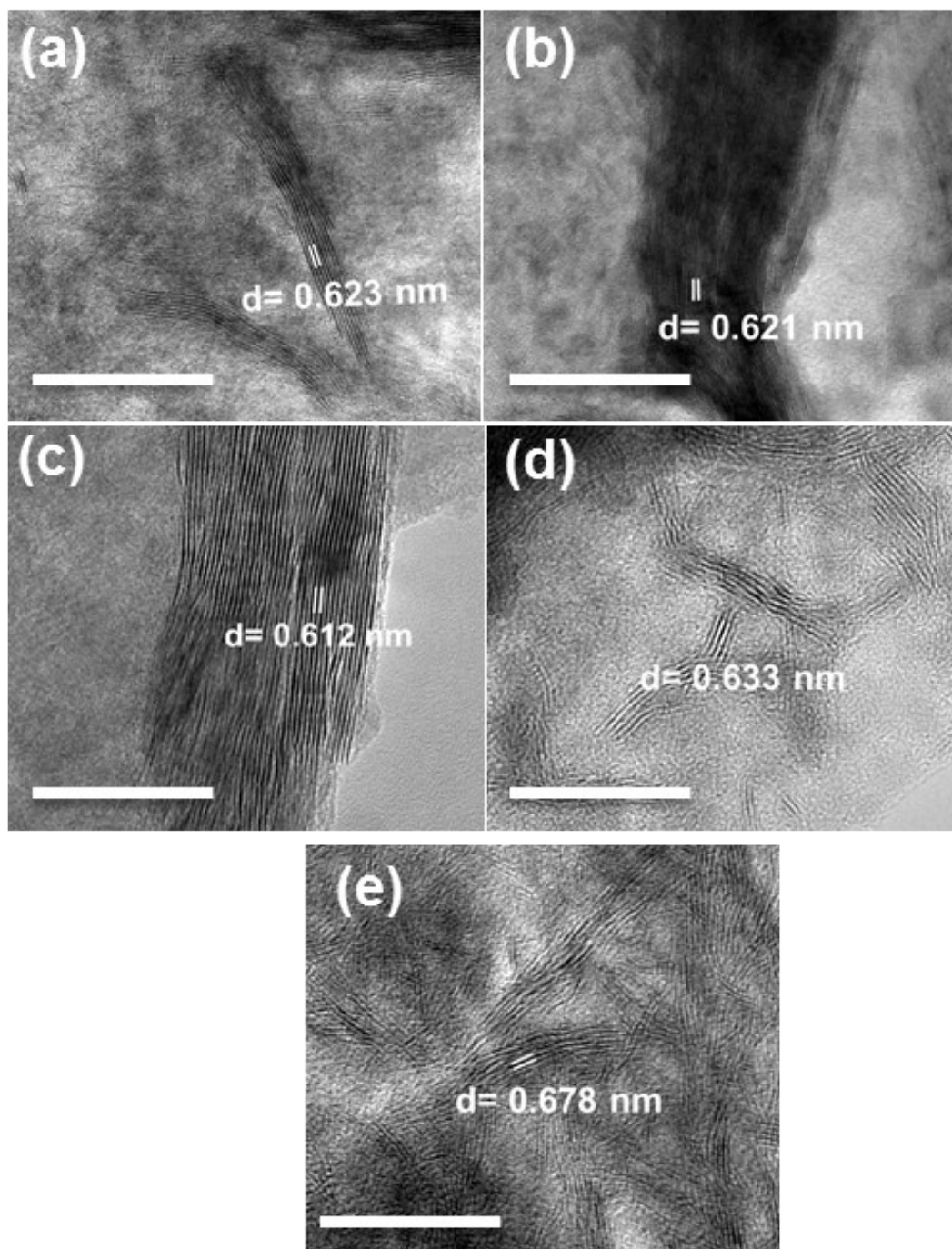


Fig. S4. Bright field TEM of undoped MoS₂ and doped MoS₂ thin films using (1) and (2) at 550 °C: (a) MoS₂, (b) 2.2% Re, (c) 3.5 % Re, (d) 3.8% Re, (e) 4.4% Re. The scale bars represent 20 nm.

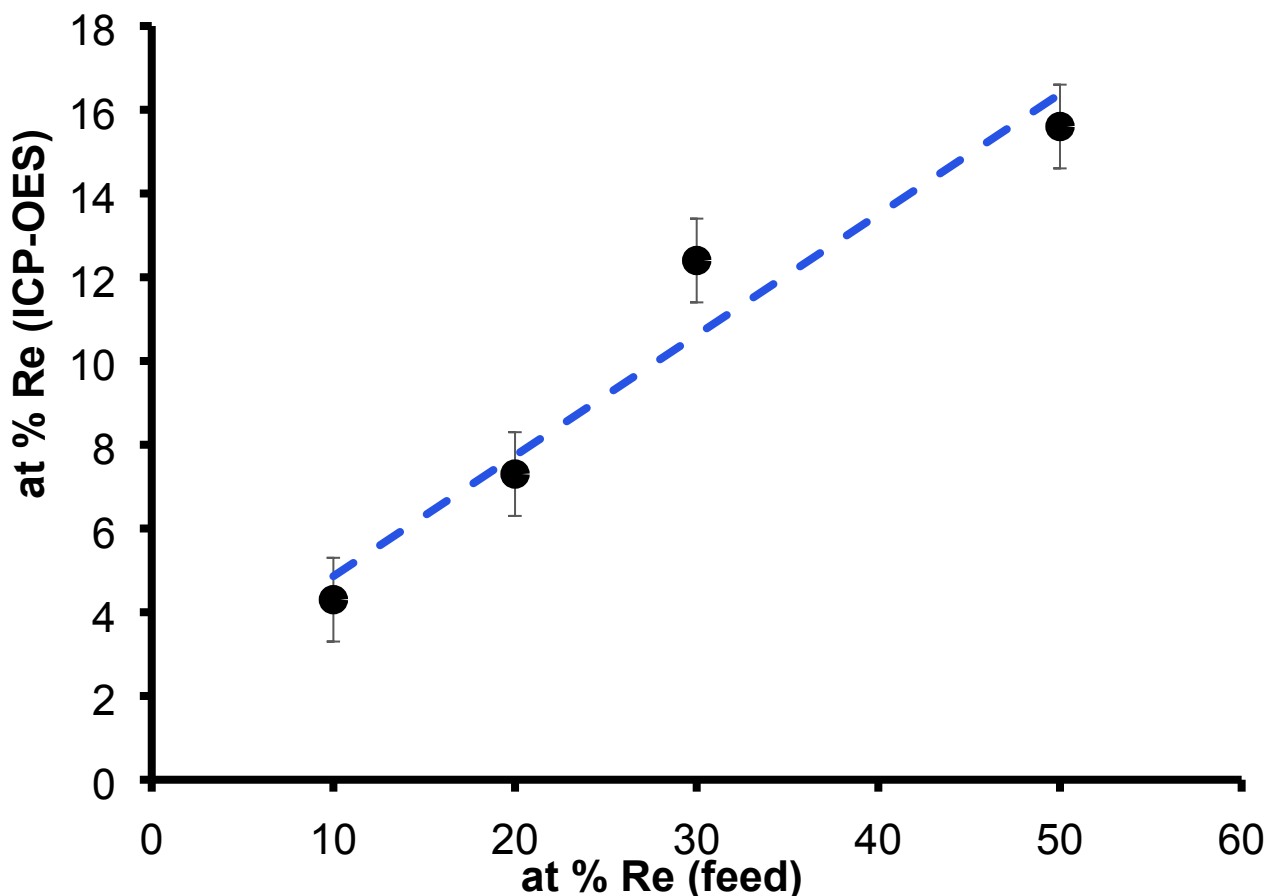


Fig. S5. Plot of mol% Re found in elemental analysis of thin films produced by AACVD using (1) and (3) at 550°C by ICP-OES, as a function of the mol% of Re in the AACVD feed.

Deposition of ReS₂ thin films using (3) as feed in AACVD

In previous work, we found it was possible to use (2) as a molecular precursor to produce ReS₂ thin films by AACVD.¹ We showed that p-XRD patterns of thin films deposited at 550 °C by AACVD onto glass substrates using precursor (2) correspond to 1T-ReS₂ with a preferred orientation in the (001) plane. This is also the case when homobimetallic complex (3) is used as the molecular precursor in AACVD (Fig 3a), with an intense reflection centred at $2\theta = 14.47^\circ$, which we again assign to the (001) plane and gives an interlayer spacing $d_{001} = 6.110 \text{ \AA}$ from the Bragg's law. This value is close to the reported (001) plane of 1T-ReS₂ (6.068 Å).²

Raman spectroscopy of the films revealed three identifiable vibrational modes that can be attributed to the successful production of ReS₂ films. E_g -like modes corresponding to the in-plane vibrations of Re atoms in ReS₂, and A_g -like modes observed at low frequency, corresponding to the out-of-plane vibrations of Re atoms (Fig. 3b). Secondary electron scanning electron microscopy (SEM) imaging reveals that these thin films of ReS₂ are uniform and comprised of small granular crystallites, interestingly without lamellar appearance, which is generally expected. Elemental analysis of the rhenium sulfide films was carried out by energy dispersive X-ray (EDX) spectroscopy and shows the grown thin films are comprised of (at%, found (calc.)): Re 37.4 (33); and S 62.6 (66). The sulfur deficiency can be attributed to the high temperatures used for thin film deposition which can, in certain cases volatilise the chalcogen component.³

It was possible to directly measure the d -spacing of the (001) plane in ReS₂ by TEM of crystallites removed from the substrate. A value of 6.06 Å was found. The likely discrepancy between the p-XRD and TEM lattice-resolution images potentially lies in the statistical relevance difference between techniques.

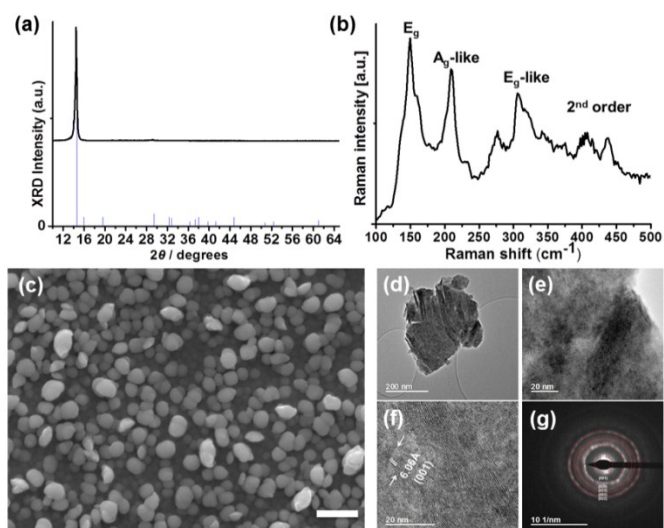


Fig S6: Characterization of ReS₂ films deposited on glass substrates by AACVD at 550 °C using [Re₂(μ-S)₂(S₂CNEt₂)₄] (**3**) as precursor. (a) Powder X-ray diffraction pattern. The blue sticks represent the standard reference pattern of ReS₂.³¹ (b) Raman spectrum with assignments. (c) Representative secondary electron SEM image of ReS₂ thin film in plan view, scale is 1 μm. (d) – (f) Bright field TEM images of a polycrystalline ReS₂ flake cleaved from the thin film. (g) Selected area electron diffraction SAED pattern associated with the same ReS₂ flake as imaged in (d).

References

1. N. Al-Dulaimi, E. A. Lewis, D. J. Lewis, S. K. Howell, S. J. Haigh and P. O'Brien, *Chem. Commun.*, 2016, **52**, 7878-7881.
2. J. Wildervanck and F. Jellinek, *J. Alloys Compd.*, 1971, **24**, 73-81.
3. M. Afzaal, M. A. Malik and P. O'Brien, *J. Mater. Chem.*, 2010, **20**, 4031-4040.